

**October 28, 2013**

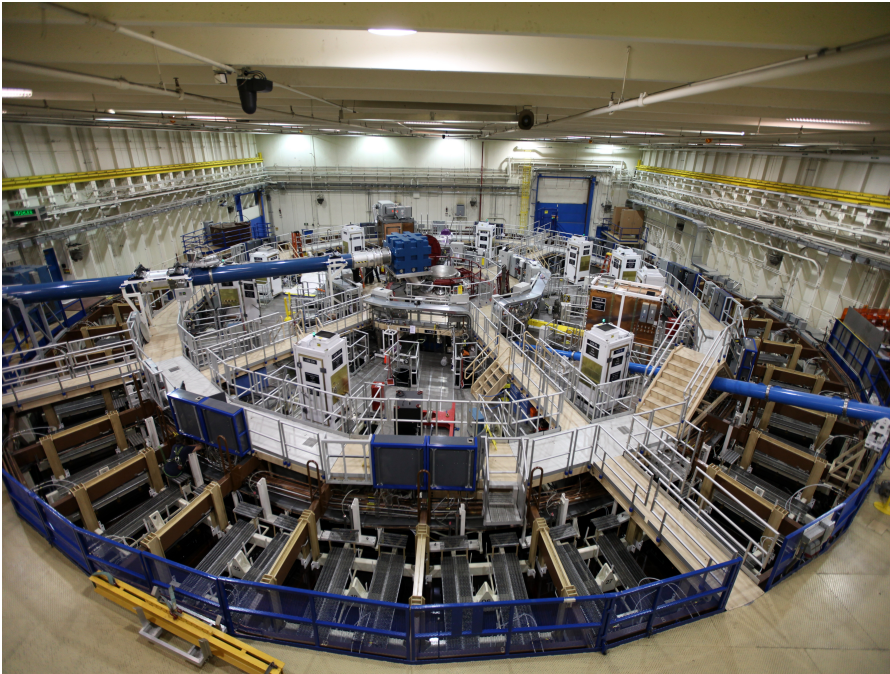
# **Development of a High-Speed Multi-frame Hybrid CMOS Sensor**

**John Porter**  
**Sandia National Laboratories**

## Project team

- **ASIC**
  - Liam Claus and Gideon Robertson
- **Photodiode array**
  - Rex Kay, Doug Trotter, and Andy Pomerene
- **Systems electronics and integration**
  - Marcos Sanchez and John Stahoviak
- **Packaging**
  - Lu Fang
- **Fabrication**
  - MESA-fab team
- **X-ray testing**
  - Mark Kimmel

# Motivation



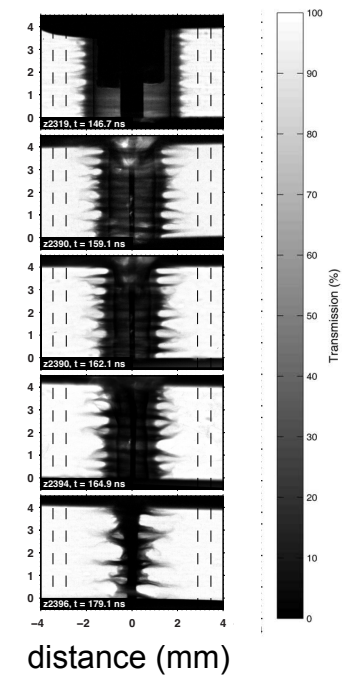
$t = 147 \text{ ns}$

$t = 159 \text{ ns}$

$t = 162 \text{ ns}$

$t = 165 \text{ ns}$

$t = 179 \text{ ns}$



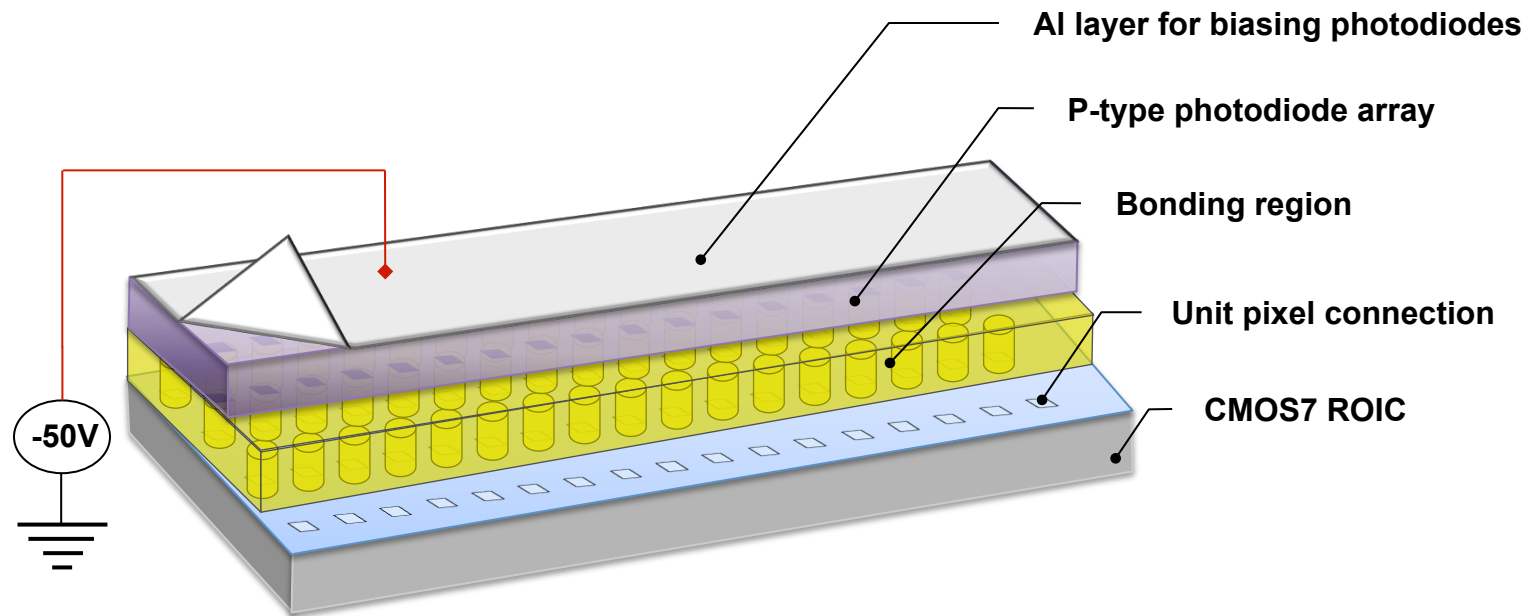
R. D. McBride, et. al., Physics of Plasmas,  
20, 056309 (2013)

## X-ray sensor performance goals

- **25  $\mu\text{m}$  x 25  $\mu\text{m}$  pixel size**
  - 100% diode fill factor
- **2-4 frames per pixel**
  - limited by size of transistors and capacitors in Sandia's 0.35  $\mu\text{m}$  CMOS process
- **1 nsec min. integration time (limited by speed of Sandia's 0.35  $\mu\text{m}$  process)**
  - asynchronous frame capture time
  - maximum integration time of order 500 msec without cooling (determined by time scale for capacitor charge leakage)
- **1 nsec min. time interval between frames**
- **50% Q.E. for 6 keV x-rays**
- **11-bit effective dynamic range**
  - minimum detected charge of 1,500e<sup>-</sup>
  - maximum detected charge of 3,000,000e<sup>-</sup>
  - 100A maximum peak diode current
- **1024 x 448 array (25.6 mm x 11.2 mm) giving 459k pixels**
  - 25.6 mm limited by size of mask tool (reticle) at Sandia's CMOS Fab
  - 11.2 mm limited by distortion of 1 nsec gate signals (timing skew across array)
- **Operational in Z vacuum chamber within 0.5 meters of z-pinch**

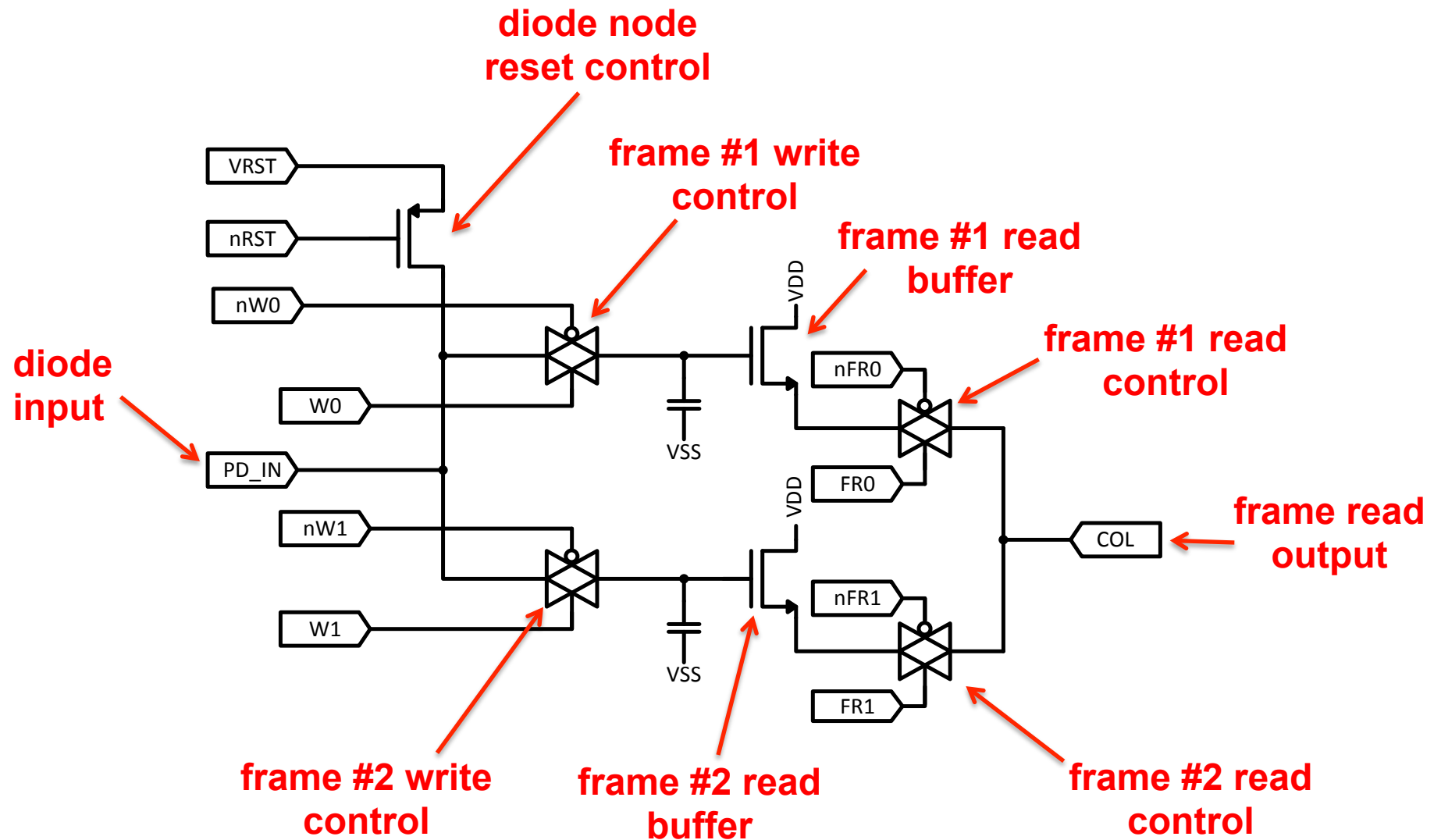


## Hybrid sensor concept

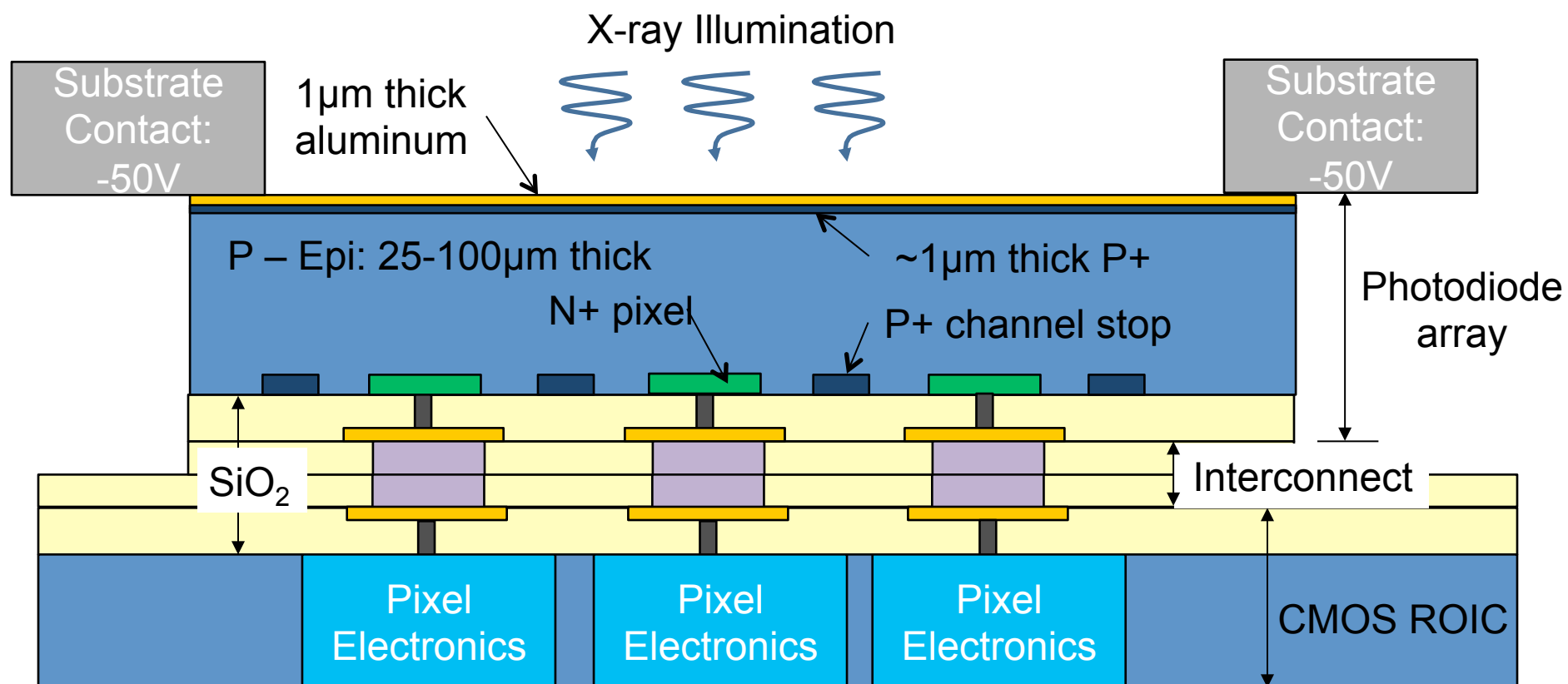


- Photodiode array converts incident radiation into electron-hole pairs
- CMOS integrated circuit stores charge from each photodiode on a 250 fF capacitor for each of 2-4 selected integration times. Integration time can be as short as 1 nsec.
- Photodiode array is connected to CMOS integrated circuit by wafer-to-wafer bonding

# Pixel schematic

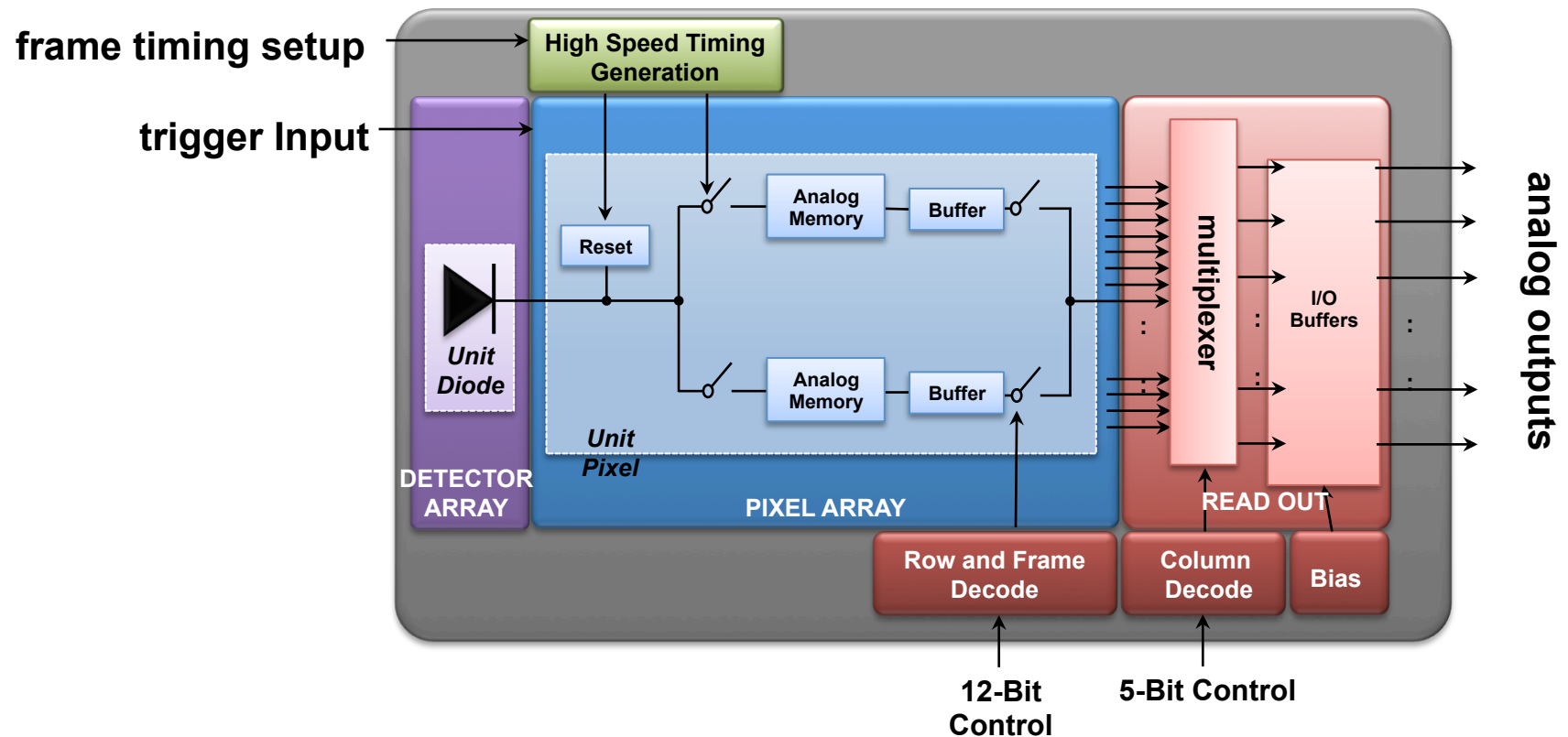


## Hybrid sensor composition



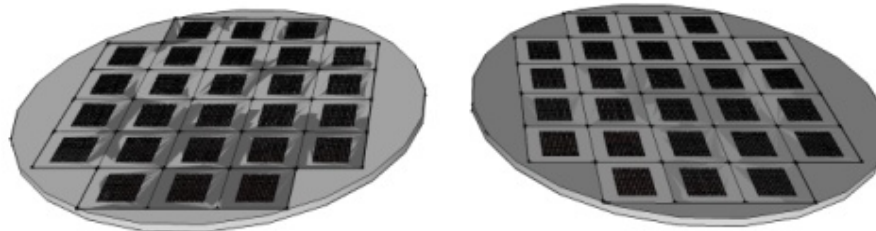
# Sensor block diagram

- Inputs
  - Power, trigger, high speed timing setup and decode signals
- Outputs
  - 16 pixel array columns (analog voltage)



## Hybrid sensor fabrication process

**6" ROIC wafer  
fabricated with  
Sandia 0.35  $\mu\text{m}$   
CMOS7 process**

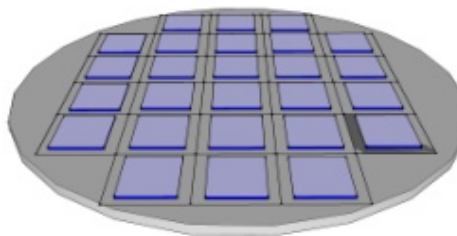


**6" photodiode wafer  
fabricated at Sandia**

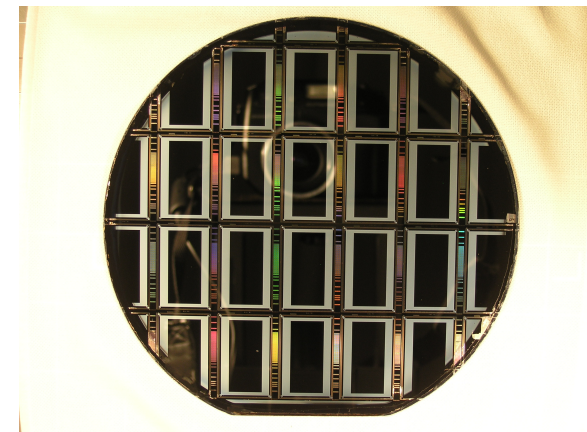
**photodiode wafer flipped  
and bonded to ROIC  
wafer by Ziptronix, Inc.**



**photodiode handle wafer  
removed, Al electrode  
applied, ROIC bond pads  
exposed to enable packaging**

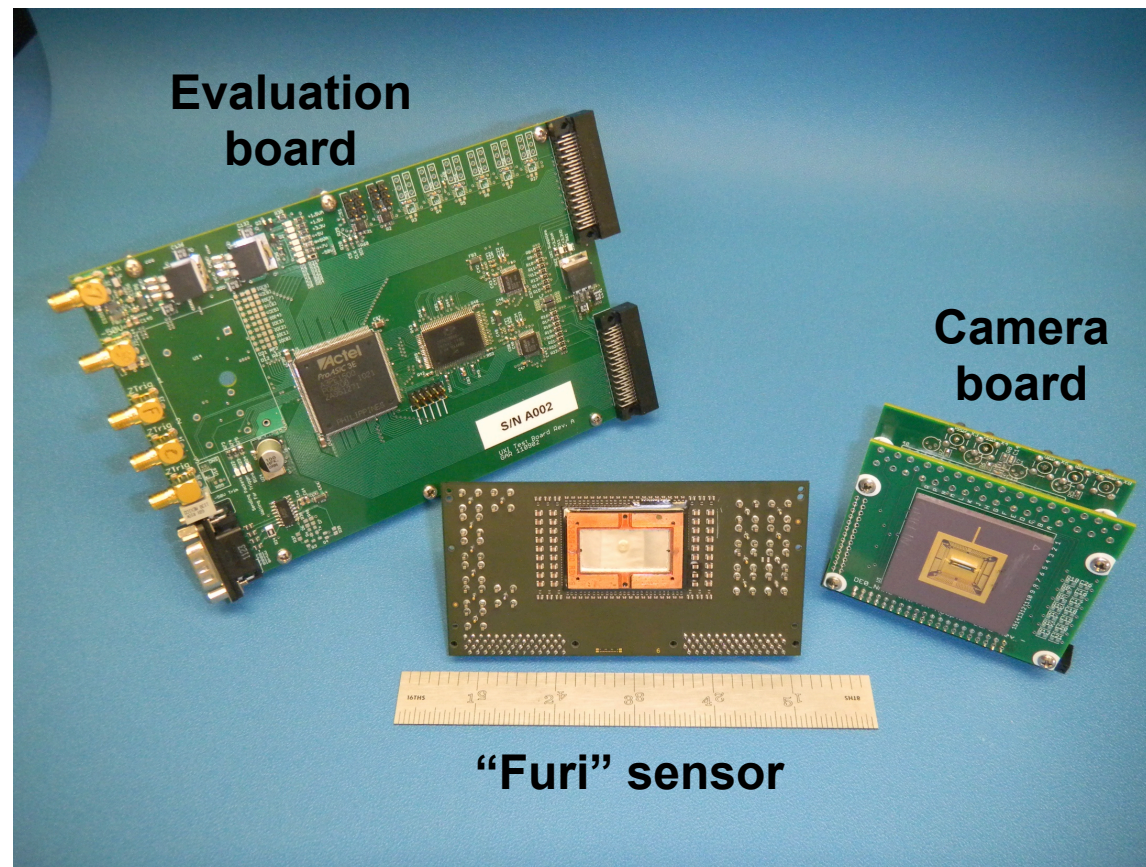


**Photo of hybridized  
sensor after die sawing**



## Sensor and system electronics

- Inputs: 7V power, -50V diode bias, trigger
- Outputs: clock monitor, Frame 0 and Frame 1 monitors, serial communication computer interface





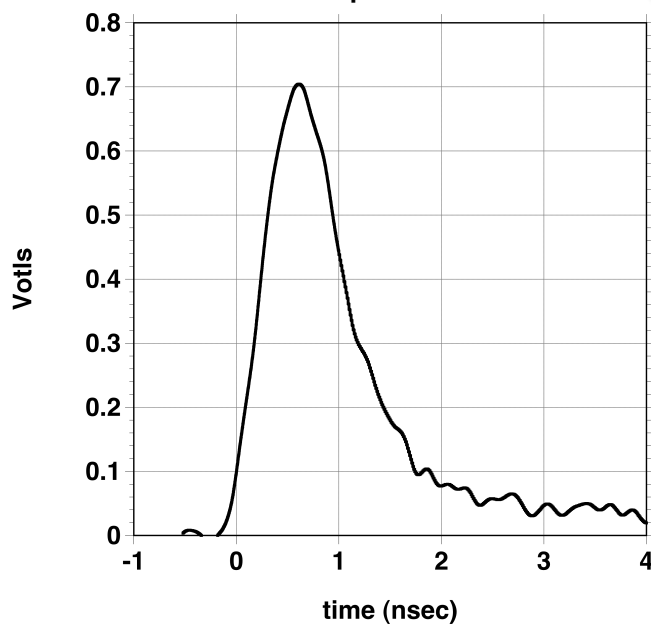
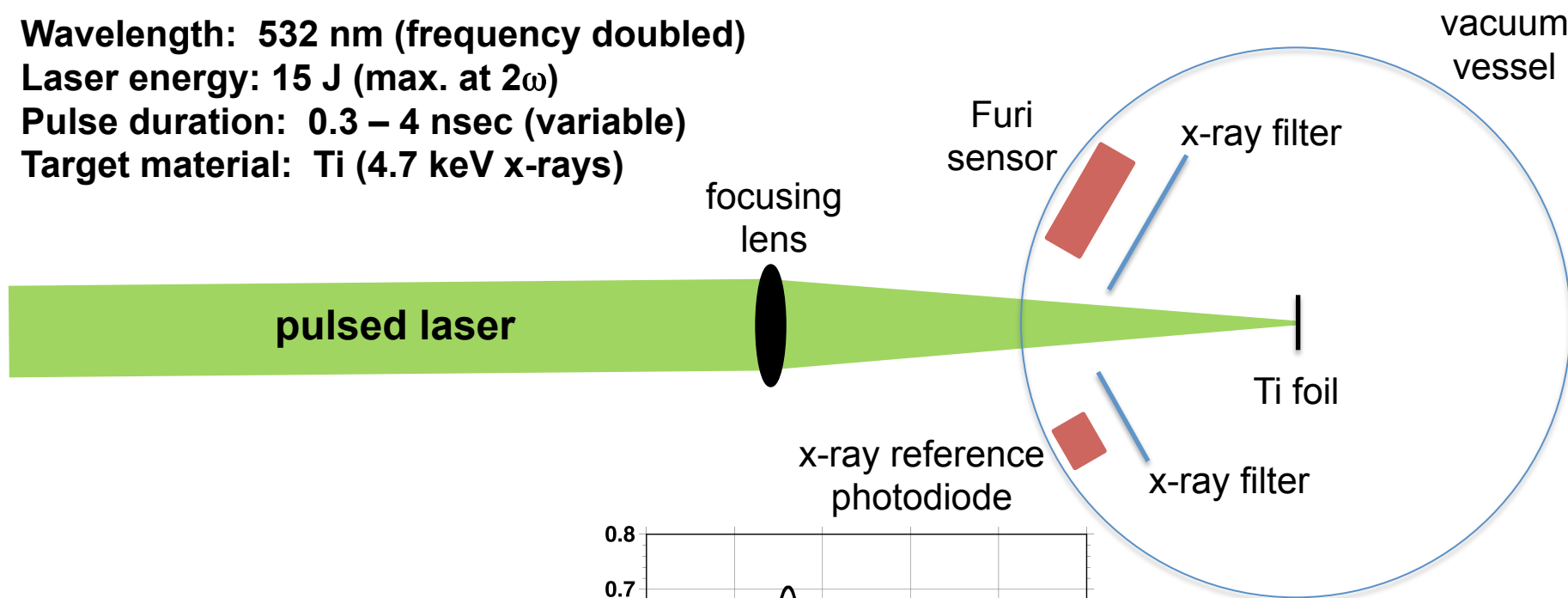
## x-ray characterization setup

**Wavelength: 532 nm (frequency doubled)**

**Laser energy: 15 J (max. at  $2\omega$ )**

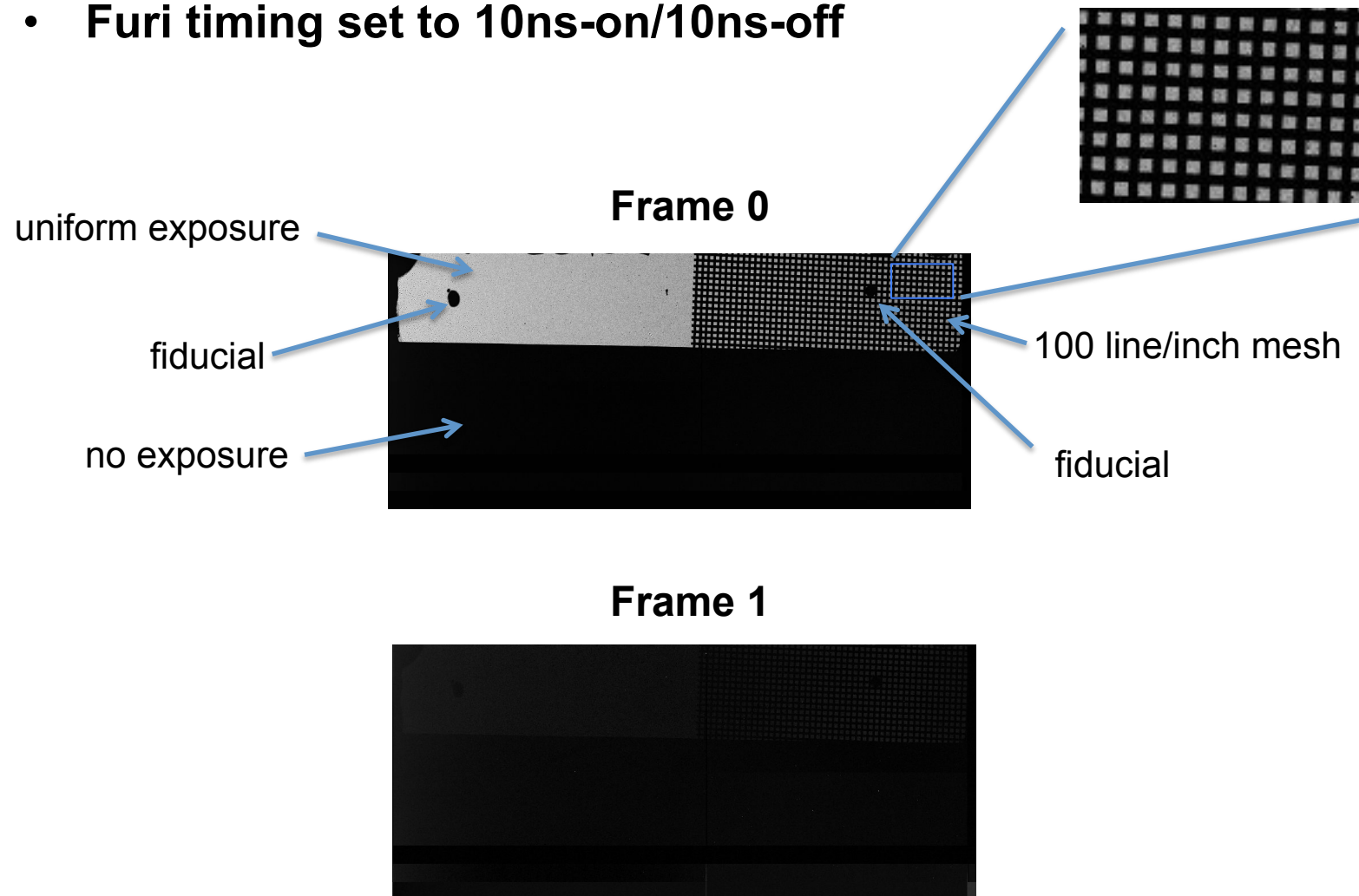
**Pulse duration: 0.3 – 4 nsec (variable)**

**Target material: Ti (4.7 keV x-rays)**



## X-ray measurements

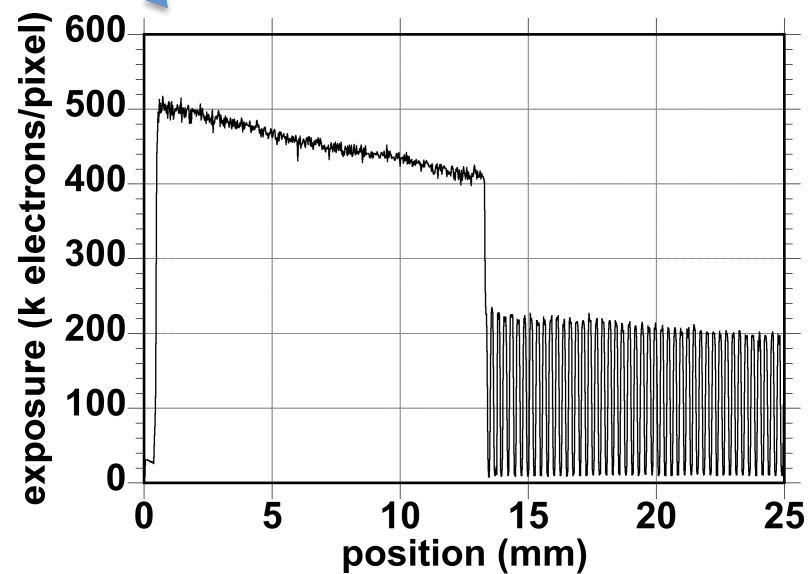
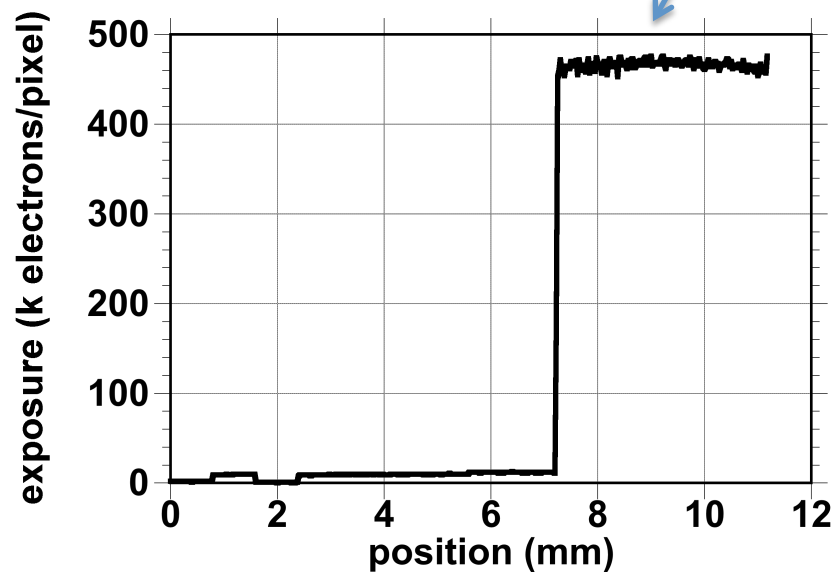
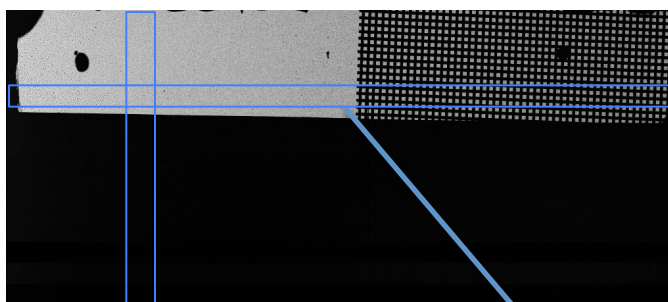
- 1ns x-ray pulse centered on Frame 0
- Furi timing set to 10ns-on/10ns-off



## Image lineouts

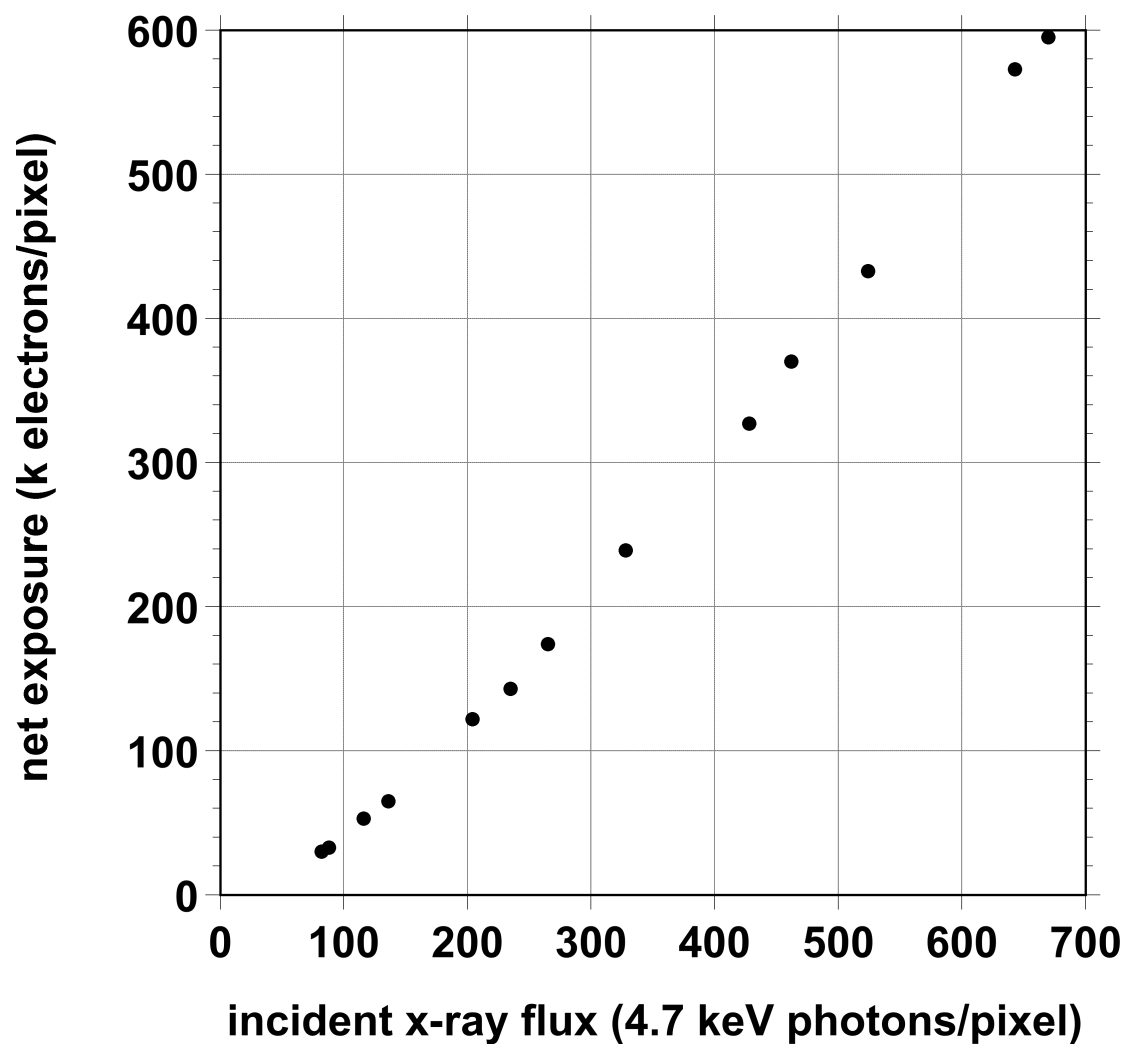
- 1ns x-ray pulse centered on Frame 0
- Furi timing set to 10ns-on/10ns-off

Frame 0

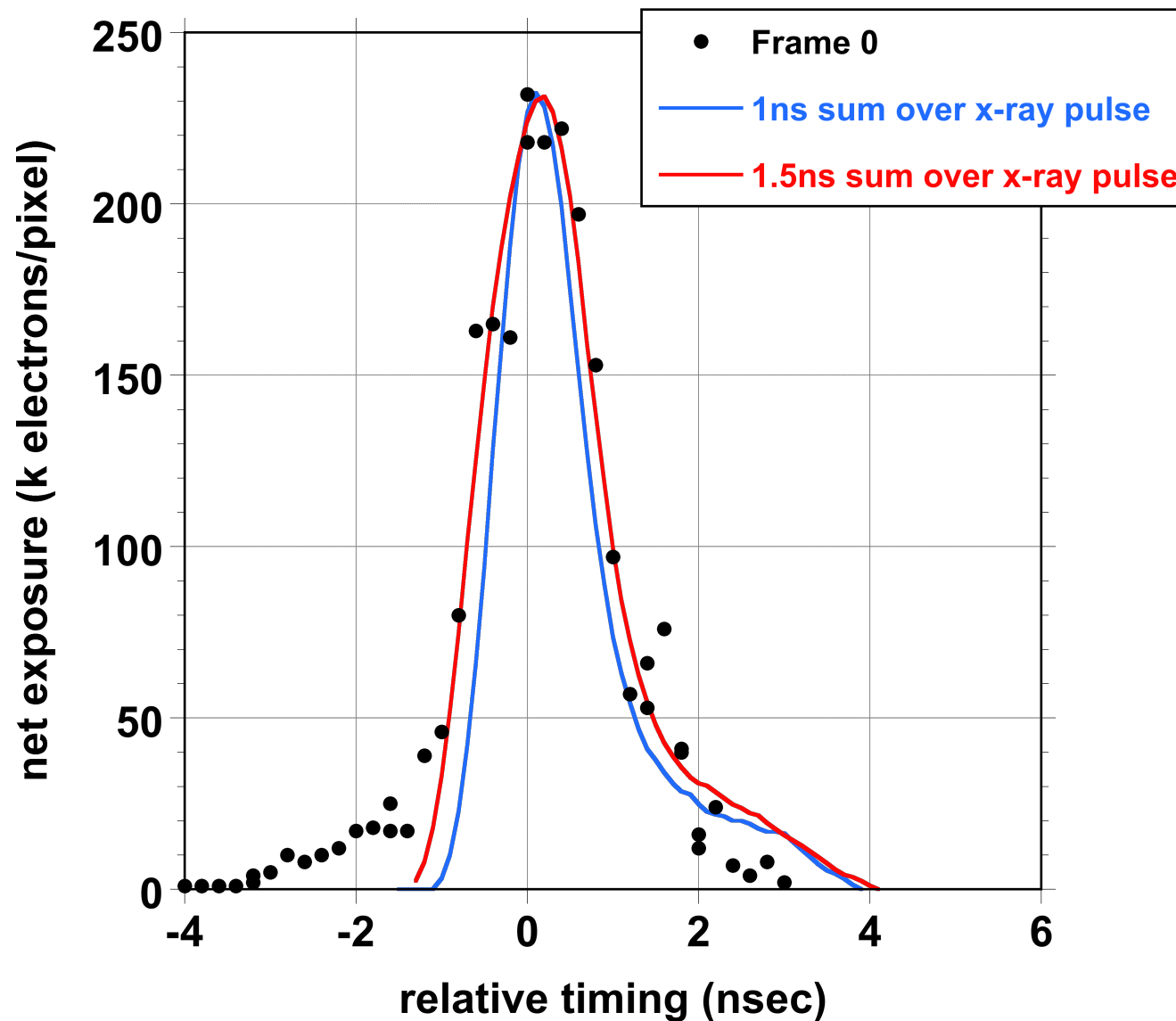


## x-ray sensitivity

x-ray pulse centered in Frame 0 with  
timing set for 10ns integration window



## Time response compared to x-ray pulse



## Near term plans

- **“Furi”**
  - Continued characterization
  - Refinement of modeling and simulation
  - Move to more compact and robust systems electronics
  - Integrate into Z experiments
  
- **Interlaced 8-frame, 1024 x 448 pixel x-ray sensor- “Hippogriff”**
  - Options of 2 frames with 1024x448 active pixels, 4 frames with 512x448 active pixels, or 8 frames with 256x448 active pixels
  - Improved frame-to-frame isolation
  - In Fabrication with packaged cameras available for initial use by February 2014
  
- **4-frame, 512 x 512 pixel sensor with optimized sensitivity for electrons (down to 1 keV), soft x-rays (down to 100 eV), and blue light (350 nm) - “Icarus”**
  - Change polarity of diode and CMOS pixel
  - Characterization of prototype diodes underway
  - Interlaced 8-frame capability
  - Designed for close packing of 2-4 die to create 1024x512 or 1024x1024 pixel sensors
  - Signal capture range per pixel modified to match lower energy electrons and x-rays (250e<sup>-</sup> to 500,000e<sup>-</sup>)
  - Fabrication planned to begin in November with packaged camera available in June 2014